



Docket No.: P2001,0011

2823

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By: Markus Nolff

Date: April 8, 2003

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor : Alfred Kersch
Applic. No. : 10/047,814
Filed : January 15, 2002
Title : Reaction Chamber for Processing a Substrate Wafer, and
Method for Operating the Chamber
Examiner : William D. Coleman - Art Unit: 2823

R E S P O N S E

Hon. Commissioner of Patents and Trademarks,
Washington, D. C. 20231

Sir:

Responsive to the Office Action dated March 25, 2003, the following remarks are made:

In deference to the restriction requirement on pages 2 and 3 of the above-identified Office Action, applicants elect group I, claims 1-8, for prosecution at this time.

Applicants reserve the right to file a divisional application including the device claims of group II at a later date.

In view of the foregoing, the early issuance of an Action on the merits of claims 1-8 is solicited.

Respectfully submitted,

Markus Nolff
For Applicant

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Date: April 8, 2003

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